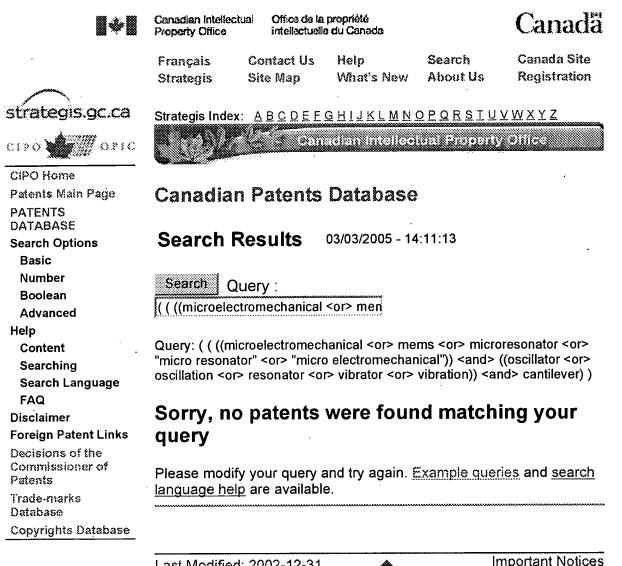
	Туре	L #	Hits	Search Text	DBs
1	IS&R	L1	2	(("4012648") or ("3913195")).PN.	USPAT
2	BRS	L2	262	(mems or microelectromechanical or "micro electromechanical") adj4 (oscillat\$3 or vibrat\$3 or resonat\$3)	USPAT; USOCR; EPO; JPO; DERWEN T; IBM_TD B
3	BRS	L3	50	mircoresonator or "micro resonator"	USPAT
4	BRS	L4	75	mircoresonator or "micro resonator"	USOCR; EPO; JPO; DERWEN T; IBM_TD B

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[Search Summary] Results of searching in PCT (Full Text) for: ((mems or microelectromechanical or "micro mechanical" or microresonator or "micro resonator")) and ((oscillator or resonator or vibration or oscillation or vibrator)) and cantilever and ((mounting or pedestal)): 61 records Showing records 1 to 25 of 61 :						
2000000000	Next 25 records Start At					
Refine Search ((mems or microelectromechanical or "micro mechan						
	Title					
1.	(WO 2005/017937) SENSOR ARRAY FOR MEASURING PLASMA CHARACTERISTICS IN PLASMA PROCESSING ENVIROMENTS					
2.	(WO 2005/008443) DISTRIBUTED SENSOR ARRAY FOR FLUID CONTAMINANT MONITORING					
3.	(WO 2005/006273) PORTABLE MOTION DETECTOR AND ALARM SYSTEM AND METHOD					
4.	(WO 2005/002858) A THERMAL ACTUATOR AND LIQUID DROP EMITTER					
5.	(WO 2005/001903) PULSE DRIVE OF RESONANT MEMS DEVICES					
6.	(WO 2004/095696) TEMPERATURE COMPENSATION FOR SILICON MEMS RESONATOR					
7.	(WO 2004/095152) VIBRATION MONITORING IN OPTICAL AND OPTO-ELECTRONIC BEAM GUIDING SYSTEMS					
8.	(WO 2004/094956) QUANTUM TUNNELLING TRANSDUCER DEVICE					
9.	(WO 2004/084131) MEMORY DEVICES					
10.	(WO 2004/083798) TEMPERATURE SENSING DEVICES, SYSTEMS AND METHODS					
11.	(WO 2004/080886) MEMS DEVICES ON A NANOMETER SCALE					
12.	(WO 2004/055935) VARACTOR APPARATUSES AND METHODS [Repub: 10.09.2004]					
13.	(WO 2004/068218) OPTICAL BEAM SCANNING SYSTEM FOR COMPACT IMAGE DISPLAY OR IMAGE ACQUISITION					
14.	(WO 2004/055935) VARACTOR APPARATUSES AND METHODS					
15.	(WO 2004/051744) MEMS CONTROL CHIP INTEGRATION					
16.	(WO 2004/037712) METHOD FOR PRODUCING A PACKAGED INTEGRATED CIRCUIT					
17.	(WO 2004/025676) MECHANICALLY BI-STABLE MEMS RELAY DEVICE					
18.	(WO 2004/012201) METHOD OF AND APPARATUS FOR CALIBRATING CANTILEVERS					
19.	(WO 2004/001807) CONSTRUCTION STRUCTURES AND MANUFACTURING PROCESSES FOR PROBE CARD ASSEMBLIES AND PACKAGES HAVING WAFER LEVEL SPRINGS					
20.	(WO 03/072486) MEMS DEVICES AND METHODS OF MANUFACTURE					
	(WO 03/069355) ACCELERATION SENSOR					
22.	(WO 03/049592) GATEWAY PLATFORM FOR BIOLOGICAL MONITORING AND DELIVERY OF THERAPEUTIC COMPOUNDS					
23.	(WO 03/047307) A MINIATURE CONDENSER MICROPHONE AND FABRICATION					

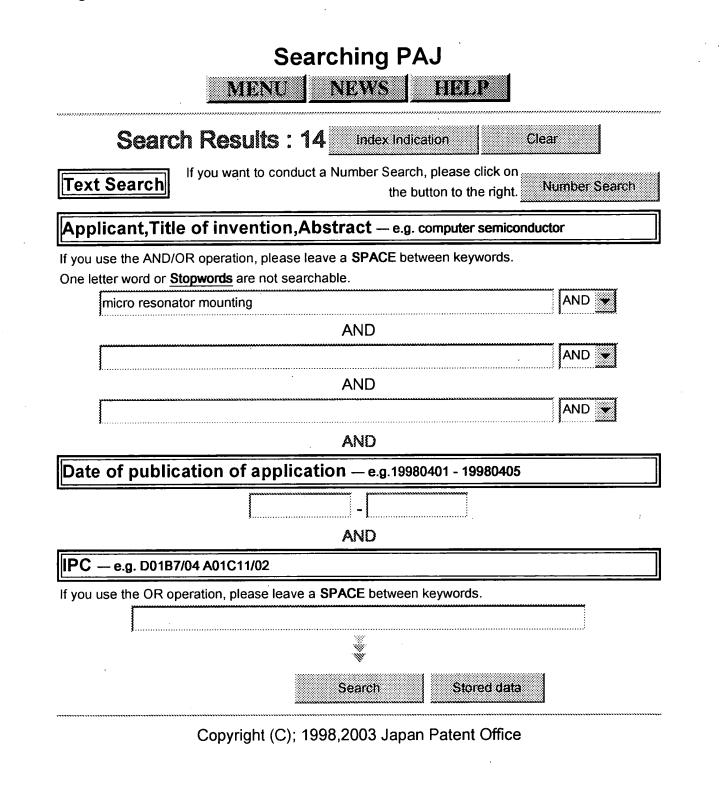
METHOD THEREFOR



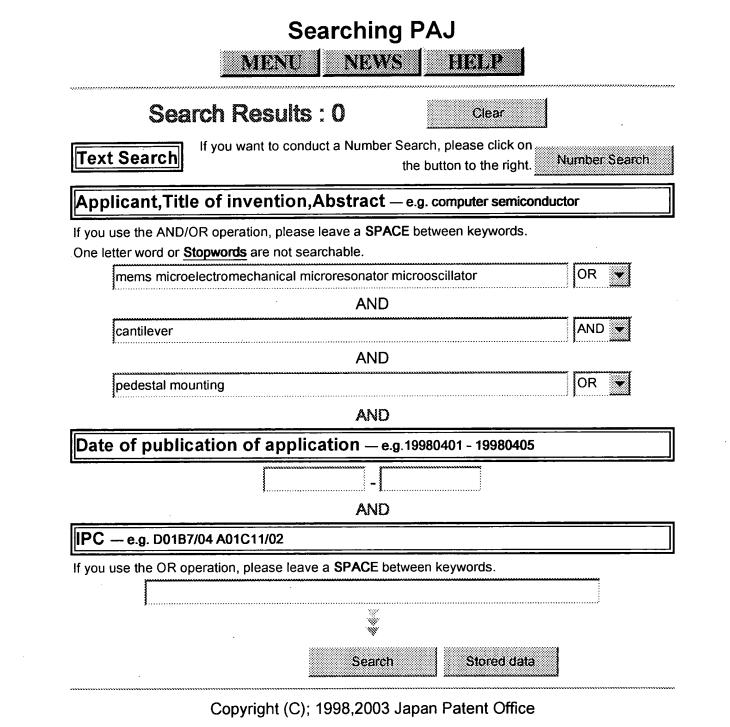
Last Modified: 2002-12-31

Important Notices

**Searching PAJ** HER N 1944 (A) Search Results : 0 Clear If you want to conduct a Number Search, please click on **Text Search** Number Search the button to the right. Applicant, Title of invention, Abstract — e.g. computer semiconductor If you use the AND/OR operation, please leave a SPACE between keywords. One letter word or Stopwords are not searchable. AND 😽 microresonator oscillator pedestal AND AND AND AND AND Date of publication of application — e.g. 19980401 - 19980405 AND IPC — e.g. D01B7/04 A01C11/02 If you use the OR operation, please leave a SPACE between keywords. Ŵ Ŵ Search Stored data Copyright (C); 1998,2003 Japan Patent Office



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